

IN THE CLAIMS

1. (Currently Amended) A method for producing an electron source comprised of plural electron emission devices, each of which has a gap and is provided with a deposit containing carbon at the gap, said plural electron emission devices connected in a matrix by plural row wirings and plural column wirings, the method comprising:

a connecting step of connecting plural pre-elements that are precursors to the plural electron emission devices, to said plural row wirings, respectively; and

a voltage applying step comprising plural sub-steps, each of which includes selecting simultaneously certain plural row wirings including plural row wirings that are not adjacent to each other and applying a voltage to the certain plural row wirings selected simultaneously, within an atmosphere containing an organic gas, wherein the sub-steps are conducted successively so that, in each sub-step, the row wirings to which the voltage is applied simultaneously include plural row wirings each of which is [[are not]] adjacent to row wirings to which the voltage was not applied in an immediately prior one of the sub-steps and therefore is not immediately sandwiched by row wirings to which the voltage was applied in the immediately prior one of the sub-steps, wherein at least one deposit is deposited as a result of the voltage applying step.

2-12. (Cancelled)

13. (Previously Presented) A method for producing an image forming

apparatus which comprises producing an electron source by the method according to claim 1 and combining thereto an image forming member for forming an image by irradiation with an electron beam from said electron source.

14. (Currently Amended) A method for producing an electron source comprised of plural electron emission devices, each of which is provided with a deposit, said plural electron emission devices connected in a matrix by plural row wirings and plural column wirings, the method comprising:

a providing step of providing plural pre-elements that are precursors to the plural electron emission devices, wherein each of the plural pre-elements is connected to each of said plural row wirings; and

a depositing step of depositing the deposit, the depositing step comprising at least three plural sub-steps, each including applying a voltage to at least one respective row wiring to deposit the deposit to at least one pre-element connected to the at least one respective row wiring, within an atmosphere containing an ingredient for the deposit, the at least three plural sub-steps being conducted successively so that, in each of the at least three plural sub-steps, the at least one respective row wiring to which the voltage is applied is not adjacent to a row wiring to which the voltage was not applied in an immediately prior one of the sub-steps and therefore is not immediately sandwiched by row wirings to which the voltage was applied in the immediately prior one of the sub-steps.

15. (Previously Presented) The method according to claim 14, wherein

the voltage is applied to plural row wirings in each of the plural sub-steps.

16. (Previously Presented) The method according to claim 15, wherein the plural row wirings to which the voltage is applied in each of the plural sub-steps are not adjacent each other.

17. (Previously Presented) The method according to claim 14, wherein the deposit contains at least carbon.

18. (Previously Presented) The method according to claim 14, wherein a differential voltage between the voltage for depositing the deposit and a voltage which is applied to at least one column wiring is applied to the at least one pre-clement, whereby the deposit is deposited to the at least one pre-element by the differential voltage.